

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

| In re Pate | ent Application of) | |
|------------|---|--|
| Paul Kev | in SHUFFLEBOTHAM et al. | Group Art Unit: 1763 |
| Applicati | on No.: 09/775,664 | Examiner: R. Zervigon |
| Filed: Fe | ebruary 5, 2001 | PEO |
| | NDUCTIVELY COUPLED) PLASMA CVD) | NSMITTAL LETTER |
| | AMENDMENT/REPLY TRA | NSMITTAL LETTER |
| | Commissioner for Patents con, D.C. 20231 | |
| Sir: | | |
| Encl | osed is a reply for the above-identified paten | t application. |
| [] | A Petition for Extension of Time is also en | closed. |
| [] | A Terminal Disclaimer and a check for [] requisite Government fee are also enclosed | |
| [] | Also enclosed is | |
| [] | Small entity status is hereby claimed. | |
| [] | Applicant(s) request continued examination [] \$370.00 (279) [] \$740.00 (179) fee due u | |
| | [] Applicant(s) previously submitted, requested. | on, for which continued examination is |
| [] | Applicant(s) request suspension of action be exceed three months from the filing of this § 1.103(c). The required fee under 37 C.F. | |
| [] | A Request for Entry and Consideration of (146/246) is also enclosed. | Submission under 37 C.F.R. § 1.129(a) |
| [X] | No additional claim fee is required. | |

[] An additional claim fee is required, and is calculated as shown below:

| | | AMENDED | CLAIMS | • | |
|---------------------------|------------------|--|-----------------|-------------------|---------------|
| | No. OF CLAIMS | HIGHEST NO. OF CLAIMS PREVIOUSLY PAID FOR | EXTRA CLAIMS | RATE | ADDT'L FEE |
| Total Claims | 20 | MINUS 20 = | 0 | × \$18.00 (103) = | |
| Independent Claims | 2 | MINUS 3 = | 0 | · \$84.00 (102) = | |
| If Amendment adds m | ultiple depende | ent claims, add \$280 | 0.00 (104) | | |
| Total Amendment Fee | | | | | |
| If small entity status is | claimed, subt | ract 50% of Total A | mendment Fe | e | |
| TOTAL ADDITIONA | L FEE DUE | FOR THIS AMEN | DMENT | | |

| [|] | A claim fee in the ar | nount of \$ | is enclosed. |
|---|---|-----------------------|----------------------|--------------|
| [|] | Charge \$ | to Deposit Account N | o. 02-4800. |

The Commissioner is hereby authorized to charge any appropriate fees under 37 C.F.R. §§ 1.16, 1.17, 1.20(d) and 1.21 that may be required by this paper, and to credit any overpayment, to Deposit Account No. 02-4800. This paper is submitted in duplicate.

Respectfully submitted,

BURNS, DOANE, SWECKER & MATHIS, L.L.P.

Edward A. Brown

By:

Registration No. 35,033

P.O. Box 1404 Alexandria, Virginia 22313-1404 (703) 836-6620

Date: February 7, 2002



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

| |) |
|---|---|
| Paul Kevin SHUFFLEBOTHAM et al. |) Group Art Unit: 1763 |
| Application No.: 09/775,664 |) Examiner: R. Zervigon |
| Filed: February 5, 2001 |)) |
| For: INDUCTIVELY COUPLED PLASMA CVD | PECA. |
| 4.3.6773 | JIDMENIE S |
| AMEN | NDMENT COLUMN TO THE PROPERTY OF THE PROPERTY |
| Assistant Commissioner for Patents Washington, D.C. 20231 | NDMENT PER TOO TOO |

AMENDMENT

Sir:

In response to the Office Action dated November 9, 2001, please amend the aboveidentified application as follows:

IN THE SPECIFICATION:

Kindly replace the paragraph beginning at page 6, line 3, with the following:

FIG. 1 shows a ICP reactor 20 which can process substrates with high density plasma. Suitable ICP reactors include TCP™ systems from Lam Research Corp., Fremont, CA. See also Ogle, U.S. Patent No. 4,948,458 which is hereby incorporated by reference herein. The reactor includes a process chamber 21 in which plasma 22 is generated adjacent substrate 23. The substrate is supported on water cooled substrate support 24 and temperature control of the substrate is achieved by supplying helium gas through conduit 25 to a space between the substrate and the substrate support. The substrate support can